

Title (en)  
ATOMIC FORCE MICROSCOPY PROBE

Title (de)  
RASTERKRAFTMIKROSKOPIESONDE

Title (fr)  
SONDE POUR MICROSCOPIE A FORCE ATOMIQUE

Publication  
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Application  
**EP 08805499 A 20080423**

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Abstract (en)  
[origin: WO2008148951A1] The invention relates to an atomic force microscopy probe (SM) including a micromechanical resonator (RMM) and a tip for atomic force microscopy (P1) protruding from said resonator, characterised in that it also comprises a means (EL1) for selectively exciting an oscillation mode of the volume of said resonator (RMM), and in that said tip for atomic force microscopy (P1, P1') protrudes from said resonator substantially in correspondence with a ventral point (PV1) of said volume oscillation mode. The invention also relates to an atomic force microscope including such a probe (SM'), and to an atomic force microscopy method involving the use of such a probe.

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**G01N 13/16**; **G12B 21/08**

IPC 8 full level  
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Citation (search report)  
See references of WO 2008148951A1

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AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MT NL NO PL PT RO SE SI SK TR

Designated extension state (EPC)  
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DOCDB simple family (publication)  
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